

PATENT ASSIGNMENT

Electronic Version v1.1

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SUBMISSION TYPE:

NEW ASSIGNMENT

NATURE OF CONVEYANCE:

ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
TRU VUE, INC.	08/07/2009

RECEIVING PARTY DATA

Name:	Applied Materials, Inc.
Street Address:	3050 Bowers Avenue
City:	Santa Clara
State/Country:	CALIFORNIA
Postal Code:	95054

PROPERTY NUMBERS Total: 10

Property Type	Number
Application Number:	07737372
Application Number:	08158729
Application Number:	08408022
Application Number:	07600203
Application Number:	08285869
Application Number:	08541399
Application Number:	08590811
Application Number:	08295324
Application Number:	10755183
Application Number:	10919791

CORRESPONDENCE DATA

Fax Number: (732)935-7122

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OP \$400.00 07737372

500968535

PATENT
REEL: 023264 FRAME: 0544

Correspondent Name: Alan Taboada
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Address Line 4: Shrewsbury, NEW JERSEY 07702

ATTORNEY DOCKET NUMBER:	TRUVUE TO APPLIED
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NAME OF SUBMITTER:	Alan Taboada
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Total Attachments: 2
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Exhibit B
Form of Patent Assignment

ASSIGNMENT

WHEREAS, TRU VUE, INC. (hereinafter "CORPORATION"), a company incorporated under the laws of the state of Illinois, U.S.A., and having a principal place of business at 9400 West 55th Street, McCook, IL 60525, is the assignor of interest of the inventions set forth in U.S. and foreign applications, U.S. and foreign patents, and invention alerts, listed on Appendix A hereto (collectively, the "Patent Documents");

WHEREAS, APPLIED MATERIALS, INC. (hereinafter "APPLIED MATERIALS"), a corporation organized under the laws of the State of Delaware, United States of America, and having a principal place of business at 3050 Bowers Avenue, Santa Clara, CA 95054 USA, is desirous of acquiring all title, right and interest in to and under said inventions and Patent Documents;

NOW, THEREFORE, be it known to all whom it may concern that for good and valuable consideration the receipt of which is hereby acknowledged, CORPORATION has and does hereby sell, assign, transfer and set over unto APPLIED MATERIALS, its successors and assigns, the full and exclusive right, title and interest including all rights acquired in foreign countries, in to and under said Patent Documents, including any divisions, renewals, continuations in whole or in part, substitutions, conversions, reissues, prolongations or extensions thereof, and in and to any and all letters patents to be granted and issued therefor, not only for, to and in the United States of America, its territories and possessions, but for, to and in all other countries and regions; and it has been and is hereby authorized and requested that the appropriate government agencies issue said letters patents to APPLIED MATERIALS, in accordance with this assignment. CORPORATION hereby consents to any and all procedures being taken by the said assignee in regard to the assignment of the identified Patent Documents.

THIS 7 day of August 2009.

TRU VUE, INC. (Assignor)

APPLIED MATERIALS, INC. (Assignee)

By: _____

Jane Boyce
Name: Jane Boyce
Title: President

By: _____

Don Kuwamoto
Name: Don Kuwamoto
Title: Vice President Global Sales Services

APPENDIX A

Country name	Title	Application date	Application number	Grant date	Grant number
U.S.A.	ALTERNATING CURRENT ROTATABLE SPUTTER CATHODE	8-Jan-04	10/755183	15-Jul-08	7399385
Denmark	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Spain	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Austria	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Belgium	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Canada	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	2089147	17-Apr-01	2089147
Switzerland	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Germany	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	69129658.8
France	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Japan	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Italy	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	513100/1991	5-Jul-02	3324654
Great Britain	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
Sweden	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
U.S.A.	CANTILEVER MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	31-Jul-91	91914088.9	24-Jun-98	543844
U.S.A.	MAGNET HOUSING FOR A SPUTTERING CATHODE	29-Jul-91	737372	6-Apr-93	5200049
Europe	MAGNETRON ASSEMBLY	24-Aug-94	08/295324	5-Nov-96	5571393
Hong Kong	MAGNETRON ASSEMBLY	2-Aug-05	5778128.8		
U.S.A.	MAGNETRON ASSEMBLY	2-Nov-07	7111920.5		
Japan	MAGNETRON ASSEMBLY	17-Aug-04	10/919791		
U.S.A.	ROTATING FLOATING MAGNETRON DARK-SPACE SHIELD	10-Oct-95	2007-527844		
U.S.A.	ROTATING FLOATING MAGNETRON DARK-SPACE SHIELD AND CONE END	4-Aug-94	08/541399	23-Jul-96	5539272
Canada	ROTATING MAGNETRON INCORPORATING A REMOVABLE CATHODE	17-Oct-91	08/285869	22-Oct-96	5567289
Japan	ROTATING MAGNETRON INCORPORATING A REMOVABLE CATHODE	17-Oct-91	2094252	7-May-02	2094252
U.S.A.	ROTATING MAGNETRON INCORPORATING A REMOVABLE CATHODE	18-Oct-90	3-518370	28-Jun-02	3323495
Canada	SHIELDING FOR ARC SUPPRESSION IN ROTATING MAGNETRON SPUTTERING SYSTEMS		600203	31-Mar-92	5100527
Japan	SHIELDING FOR ARC SUPPRESSION IN ROTATING MAGNETRON SPUTTERING SYSTEMS	31-Jul-91	2089149	26-Nov-02	2089149
U.S.A.	SHIELDING FOR ARC SUPPRESSION IN ROTATING MAGNETRON SPUTTERING SYSTEMS	31-Jul-91	515608/1991	30-Jan-04	3516949
U.S.A.	SHIELDING FOR ARC SUPPRESSION IN ROTATING MAGNETRON SPUTTERING SYSTEMS	21-Mar-95	08/408022	10-Mar-98	5725746
U.S.A.	SHIELDING FOR ARC SUPPRESSION IN ROTATING MAGNETRON SPUTTERING SYSTEMS	29-Nov-93	5470452	28-Nov-95	5470452
U.S.A.	SPRING-LOADED MOUNT FOR ROTATING CYLINDRICAL MAGNETRONS	24-Jan-96	08/590811	15-Apr-97	5620577

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